RESS MAIL LABEL NO.: EQ 912152586 US **DEPOSIT:**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

David Mui et al.

Serial No

09/905,172

Filed

July 13, 2001

Title

ETCH PATTERN DEFINITION USING A CVD ORGANIC LAYER AS

AN ANTI-REFLECTION COATING AND HARDMASK

1792

Confirmation No.:

2748

Examiner:

Duy Vu Nguyen Deo

Docket No.:

004227/USA02/ETCH/SILICON

Commissioner for Patents PO Box 1450 Alexandria, VA 22313-1450

PETITION TO REVIVE UNINTENTIONALLY ABANDONED APPLICATION **UNDER 37 CFR 1.137(b)**

Sir:

This Petition to Revive Unintentionally Abandoned U.S. Patent Application 09/905,172 is filed in response to the Notice of Abandonment dated October 26, 2007.

As per the Notice of Abandonment, the applicant failed to seek court review of the decision rendered by the Patent Board of Appeals and Interferences rendered July 25, 2007, and no claims had been allowed.

A new continuation application is filed herewith, in lieu of a response to the Decision mailed July 25, 2007. The entire delay in filing the required reply from the due date for the reply 11/05/2007 FRETEKI1 00000067 501047 until the filing of this petition was unintentional.

As applicant believes it has now met the requirements of the Decision mailed July 25, 2007, Applicant hereby petitions the Commissioner to grant this Petition to Revive. It is

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respectfully requested that this application be revived in order to be considered copending with the continuation application that is filed herewith.

The PTO is hereby authorized to charge the \$1540 Petition Fee and any additional fees that may be required as a result of this Petition to the undersigned attorney's PTO Deposit Account #50-1047.

Date: October 31, 2007

Respectfully submitted,

Keum J. Park Reg. No. 42,059

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